



RESPONSE UNDER 37 CFR 1.116
EXPEDITED PROCEDURE
EXAMINING GROUP 2851

00862.022246

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
Kazunori IWAMOTO et al.) : Examiner: H. Nguyen
Application No.: 09/866,600) : Group Art Unit: 2851
Filed: May 30, 2001) : Confirmation No.: 4961
For: STAGE APPARATUS WHICH SUPPORTS) :
INTERFEROMETER, STAGE POSITION) :
MEASUREMENT METHOD, PROJECTION) :
EXPOSURE APPARATUS, PROJECTION) :
EXPOSURE APPARATUS MAINTENANCE) :
METHOD, SEMICONDUCTOR DEVICE) :
MANUFACTURING METHOD, AND) :
SEMICONDUCTOR MANUFACTURING FACTORY :
October 8, 2003

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT AFTER FINAL REJECTION

Sir:

In response to the Official Action dated July 8, 2003, please amend the above-identified application as follows:

10/09/2003 SSITHIB1 00000041 09866600

01 FC:1201

86.00 DP